

213345US-2 CONT

#5/A
11/28/01
A JONES

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

:

Kanefumi NAKAHARA ET AL.

: EXAMINER:

SERIAL NO.: NEW APPLICATION

:

FILED: HEREWITH

: GROUP ART UNIT:

FOR: EXPOSURE APPARATUS, LITHOGRAPHY
SYSTEM AND CONVEYING METHOD,
AND DEVICE MANUFACTURING METHOD
AND DEVICE

PRELIMINARY AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Prior to examination on the merits, please amend this application as follows:

IN THE SPECIFICATION

Please amend the specification as shown in the marked-up copy following this
amendment.

Please replace the paragraph beginning on page 1, lines 7-11, with the following:

CROSS REFERENCE TO RELATED APPLICATION

This is a continuation of International Application PCT/JP00/01075, with an
international filing date of February 25, 2000, the entire content of which being hereby
incorporated herein by reference, which was not published in English.